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Stands For Opportunity



FLORIDA SOLAR ENERGY CENTER®

Creating Energy Independence

Atmospheric Pressure Chemical Vapor Deposition of Functional Oxide Materials for Crystalline Silicon Solar Cells

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Collaboration with:



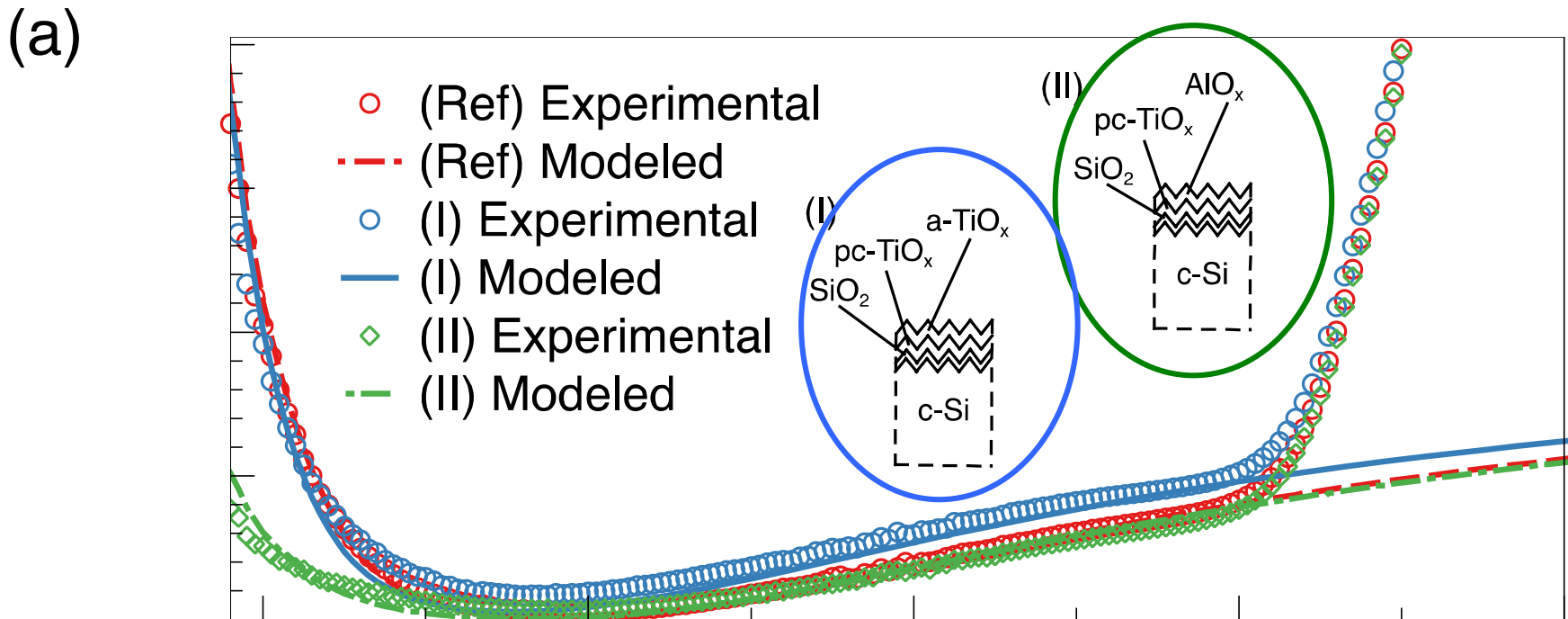
- In-line APCVD used to deposit the materials below
- Different functionalities within c-Si solar cells were explored

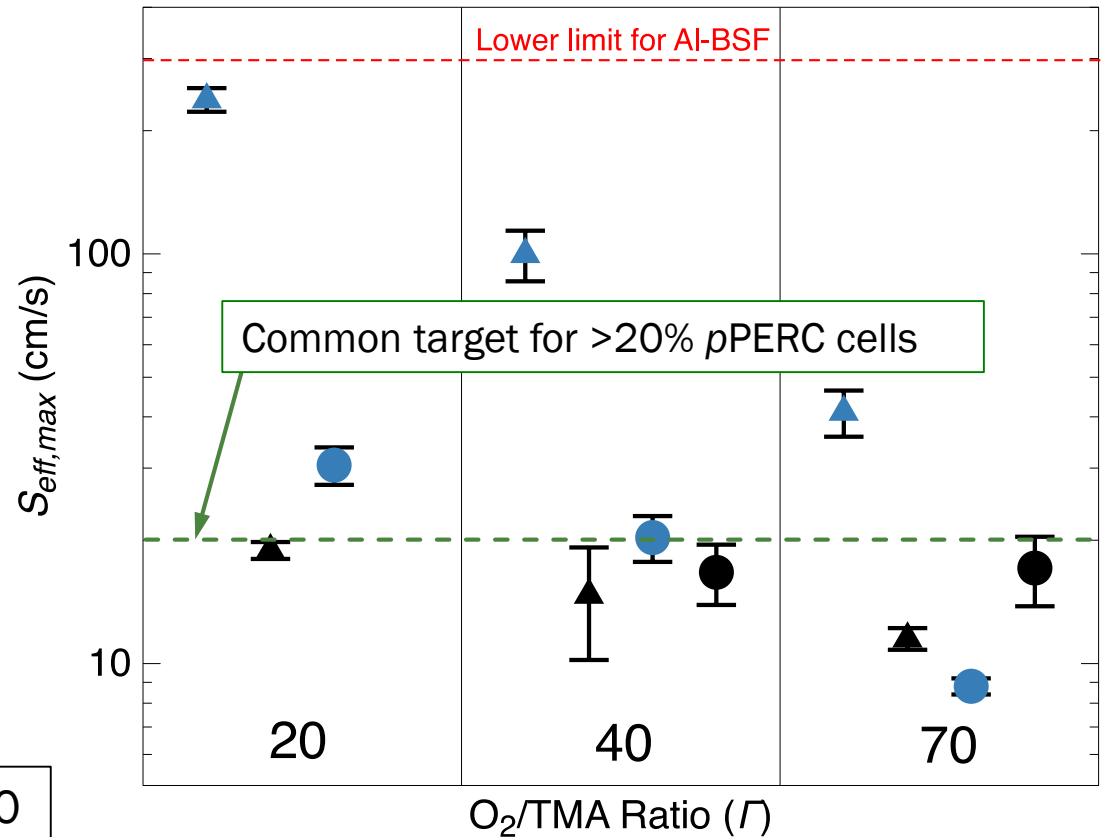
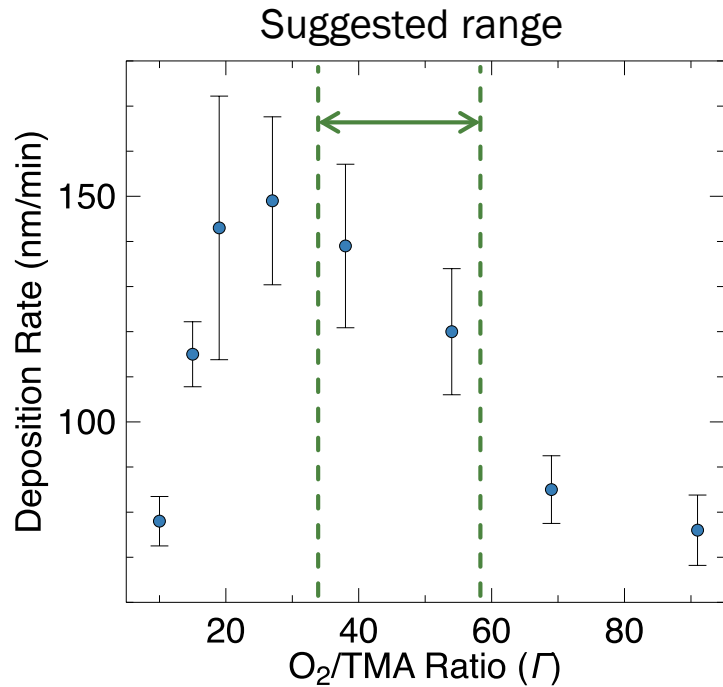
Oxide Material

B)

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- Boron dopant source and surface passivation layer
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- Results: SiO_2 passivated stacks vs. SiN_x





Optimum O_2/TMA ratio in the 35-60 range based on performance vs. throughput tradeoff.

- ▲ As-deposited AlO_x
- ▲ AlO_x after firing
- As-deposited $\text{AlO}_x + \text{SiO}_x$ capping layer
- $\text{AlO}_x + \text{SiO}_x$ after firing

- SIMS depth profiles for four groups with equivalent sheet resistances ($R_{sheet} \approx 60 \Omega/\square$)

